



Our Docket No: 42P10058

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

#710
2-25-03
JH

In re Application of:

Han-Ming Wu et al.

Examiner: Nguyen, Hung

Serial No: 09/752,938

Art Unit: 2851

Filed: December 29, 2000

For: Purging Gas from a
Photolithography Enclosure
Between a Mask Protective
Device and a Pattern Mask

TECHNICAL CENTER 2800
FEB 20 2003

RESPONSE TO OFFICE ACTION

Box Fee Amendment
Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action mailed November 1, 2002 the Applicants respectfully request that the Examiner enter the following amendments and to consider the following remarks.

FIRST CLASS CERTIFICATE OF MAILING

I hereby certify that I am causing the above-referenced correspondence to be deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and that this paper or fee has been addressed to the Assistant Commissioner for Patents, Washington, D. C. 20231

February 7, 2003

Date of Deposit

Krista Mathieson

Name of Person Mailing Correspondence

Signature

Date